

**Notice of References Cited**

Application/Control No.

10/080,696

Applicant(s)/Patent Under  
Reexamination  
GOKER, TURGUY

Examiner

Toan M Le

Art Unit

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**U.S. PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-6477432	11-2002	Chen et al.	700/51
	B	US-6556884	04-2003	Miller et al.	700/121
	C	US-5987398	11-1999	Halverson et al.	702/179
	D	US-6401054	06-2002	Andersen	702/179
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	L	US-			
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**FOREIGN PATENT DOCUMENTS**

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**NON-PATENT DOCUMENTS**

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	"Multivariate Statistical Process Control and Signature Analysis Using Eigenfactor Detection Methods", Chen et al., the 33 <sup>rd</sup> Symposium on the Interface of Computer Science and Statistics, June 2001
	V	"A Statistical Methods of Single and Multiple Response Surface Modeling", Smith et al., IEEE Transactions on Semiconductor Manufacturing, Vol. 12, No. 4, November 1999
	W	"Statistical Methods for Semiconductor Manufacturing", Boning et al., Encyclopedia of Electrical Engineering, Feb. 1999
	X	"Handbook of Statistical Methods for Engineers and Scientists", Wadsworth, Jr., McGraw-Hill, Inc., 1990

\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.